Visit by Healthcare Device Industries Association

About 20 members of the Hong Kong Medical and Healthcare Device Industries Association (HKMHDIA) visited CityU on 6 August to explore opportunities for research collaboration and tech transfer. During visits to the Product Safety and Hazard Analysis Laboratory and the Networking Laboratory, the delegates met with CityU researchers and were introduced to the University's air purification, HIV monitoring, and telemedicine technologies. The half-day event ended with a discussion and partnership matching session, and several companies have shown interest in CityU's technologies. The visit was co-organized by the HKMHDIA and the KTO.

Licensing Deals

From May to August 2010, CityU Research Limited (CityUR) signed three licensing agreements with local and national enterprises, and one marketing agreement with a global patent agency.

CityU patents marketed internationally

According to an agreement signed with an IP marketing agency, CityU's patents would be advertised on the agency's trading platform. The arrangement is expected to increase the exposure of the University's intellectual properties, making them known to potential licensees in overseas markets.

3D technology to empower designs of electronic products

Dr Peter Tsang's 3D display technology is licensed to two local companies specializing in electronic products. Dr Tsang's technology stores, distributes, and displays multiple views of the same object in the way 2D video signals are handled. This makes 3D display more affordable and accessible.

Mobile communication technology to enhance video surveillance

The WeZOOM technology developed by Prof Jia Weijia of the Computer Science Department is licensed to a mainland electronic information enterprise. WeZOOM is a software tool that connects 3G mobile network, WiFi, and the internet. With WeZOOM, video surveillance can be implemented via 3G phones, PDAs, and laptops.

Granted Patent

Apparatus and method for focused electric field enhanced plasma-based ion implantation by Prof Paul Chu (AP)

US patent no.: 7741621

Plasma-based ion implantation is useful for modifying the surface properties of materials and therefore enjoys wide industrial application. Typically, the objects to be treated are immersed in plasma from which ions are extracted and implanted in the surface of the objects. Conventional plasma-based ion implantation techniques fail to provide a single plasma source that contains ions of all possible elements, thus making it difficult to implant materials with a low melting point and high vapour pressure, such as sulphur, boron, phosphorus, silicon and geranium. The method developed by Prof Chu seeks to solve the problem stated above by generating an electron focused electric field to enhance the ionization of the plasma. The implantation material is generated by evaporating a source material in an evaporation chamber to create a vapour which is then led by a conduit to the implantation chamber.